

MENU

SEARCH

INDEX

JAPANESE

LEGAL
STATUS

1 / 1

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 03-272549

(43)Date of publication of application : 04. 12. 1991

(51)Int. Cl.

H01J 27/16

(21)Application number : 02-070753

(71)Applicant : SHIMADZU CORP

(22)Date of filing : 20. 03. 1990

(72)Inventor : FUJITA HIROYUKI

(54) HIGH FREQUENCY ION SOURCE

(57)Abstract:

PURPOSE: To construct a device concerned in a small size by forming a reflex high voltage generating part from a high frequency transformer and a rectifier circuit, and connecting the high frequency transformer between an induction coil and a capacitor either in parallel with or in series to the induction coil.

CONSTITUTION: High frequency power from a high frequency power supply 3 is given to an induction coil 2 via a capacitor 11, and a voltage obtained by superposing this output voltage of high frequency power supply 3 over the output voltage of a high voltage power supply 6 is impressed on the induction coil 2. Therein the output voltage of the high voltage power supply 3 is checked by the capacitor 11 and not applied to the high frequency power supply 6 side. A high frequency current given to the induction coil 2 is supplied to a rectifier circuit 14 via a high frequency transformer 13, and the rectifier circuit 14 generates a DC high voltage through rectification of this high frequency current, and this voltage generated is impressed on a reflex electrode 7. The eliminates use of an insulation transformer as well in the circuitry part on the induction coil 2 side as in the circuitry part on the reflex electrode 7 side, and it is only required to incorporate a high frequency transformer in smaller size. Thereby the whole device can be made smaller to a great extent.

